

"A back to back Kinoform for X6A"

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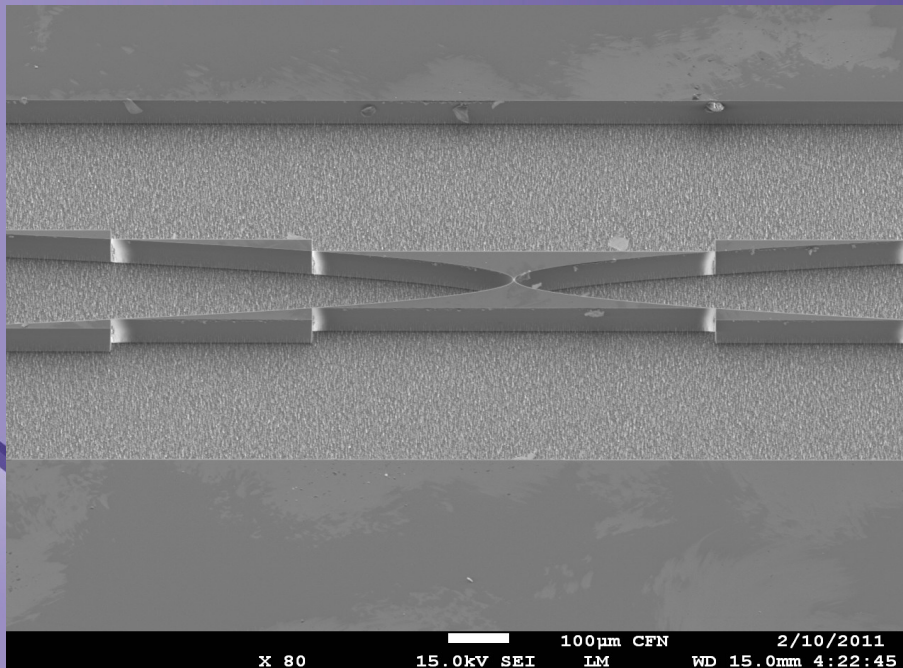
NSLS

2/14/11



SIXTY YEARS
OF DISCOVERY
1947-2007

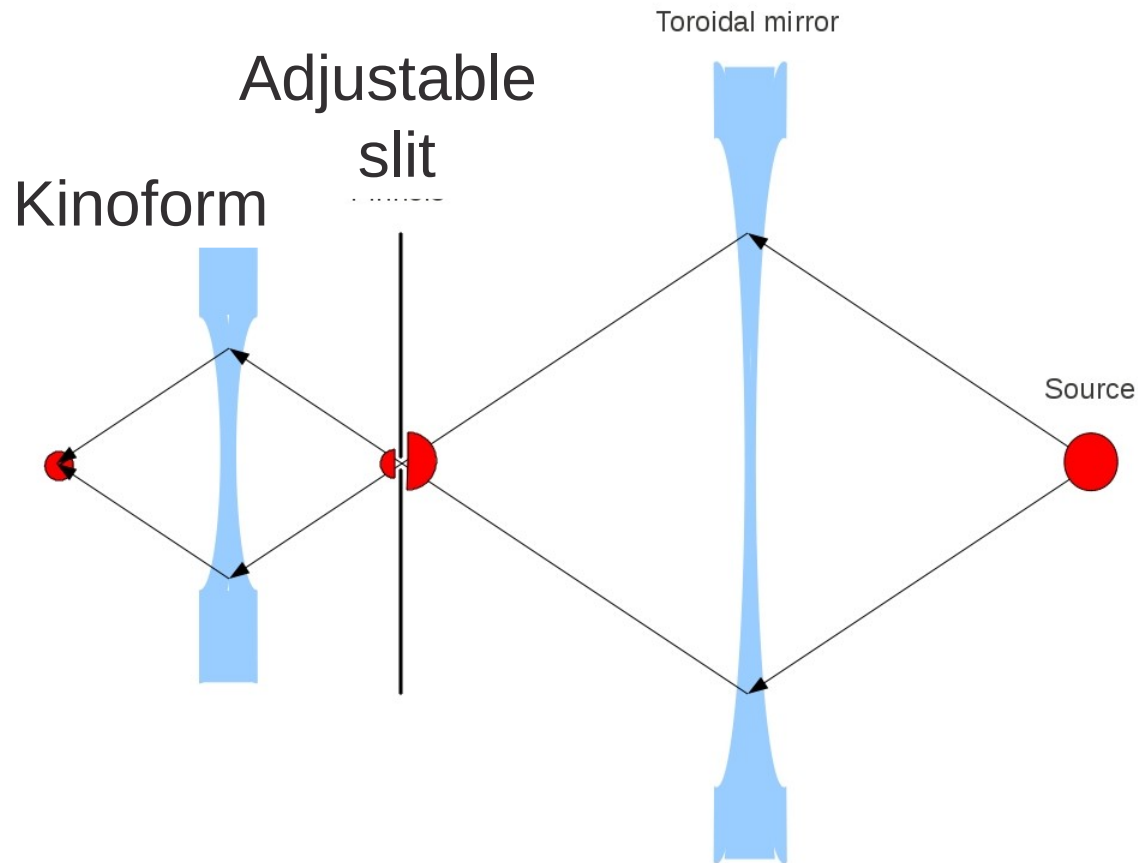
BROOKHAVEN
NATIONAL LABORATORY



Outline

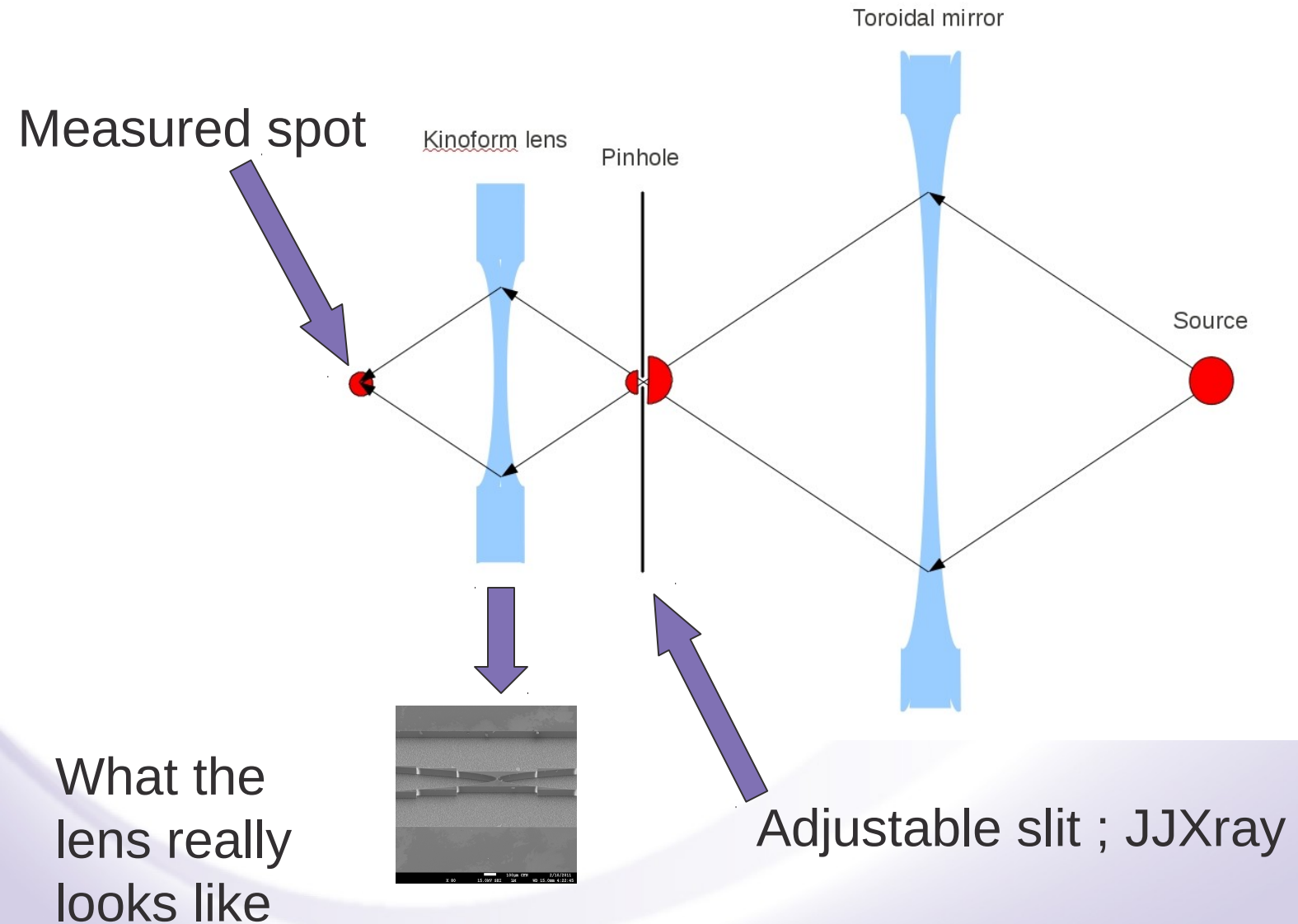
- **Summary: What we did**
- **Background**
- **Quick introduction to kinoform**
- **Some other things we have done with the kinoform**
- **Summary**

Problem: Imperfect beamlines do not focus well to give small spots;
Our solution: Implement a virtual slit using a real slit and a kinoform lens

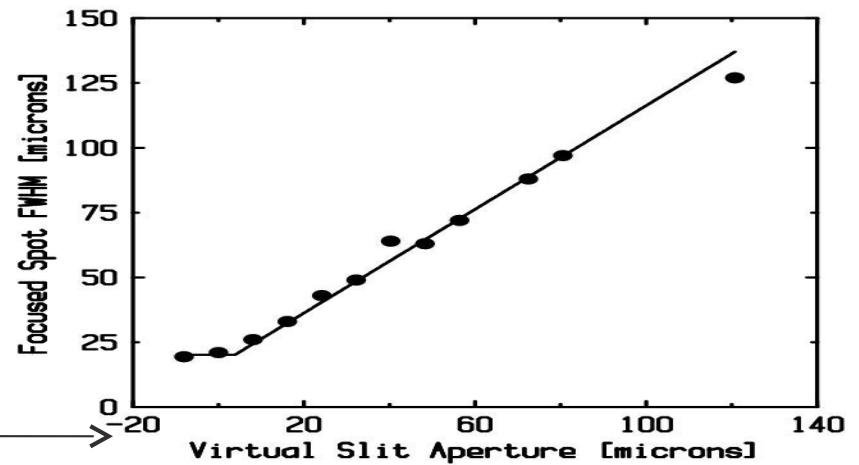


Our addition | Existing beamline

What the components look like:

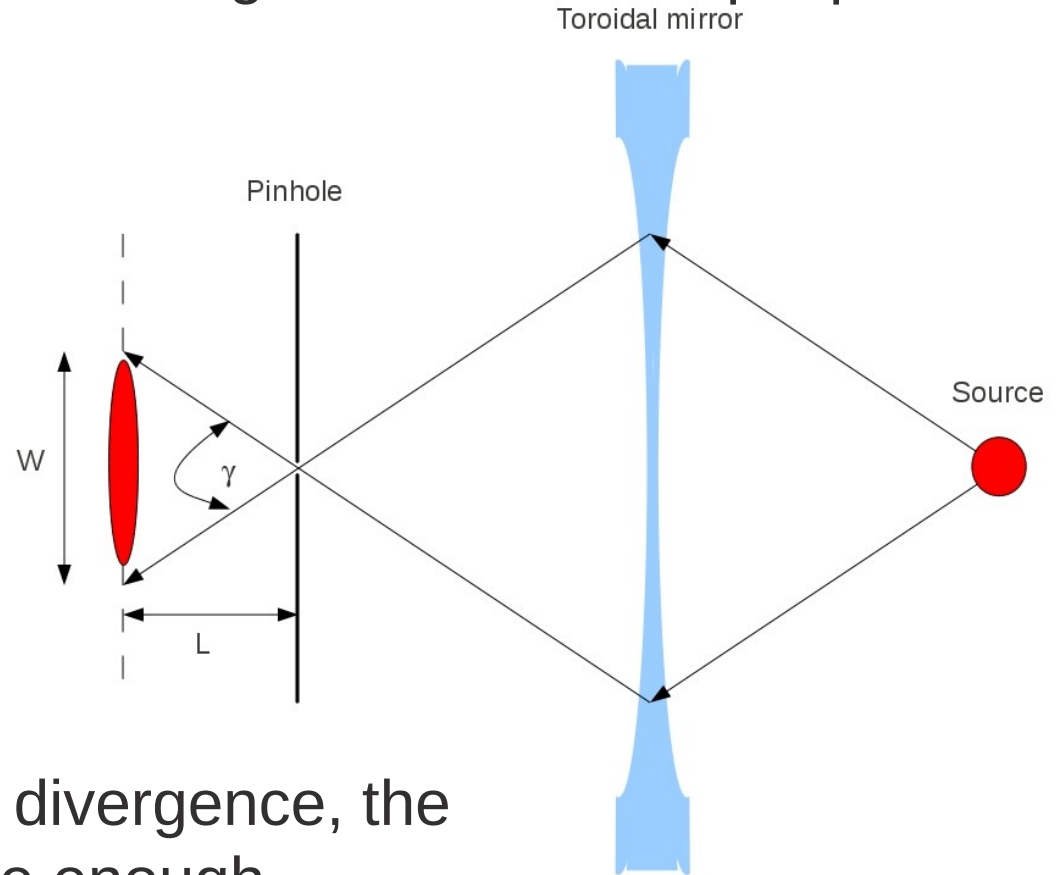


Result;
Measured spot at sample depends on slit size



20 microns spot,
Limited by measurement

Why can't we use a simpler arrangement like a simple pinhole?



Answer: Given the typical divergence, the pinhole cannot be put close enough.

If $\gamma \approx 1\text{mrad}$, $L \approx 0.3\text{m}$, then $W \approx 300\text{microns}$

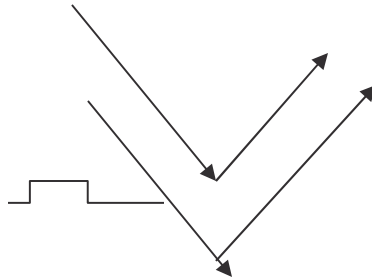
What makes a beamline imperfect?

Mirrors

Consider a mirror with a bump on it

The path length difference caused by bump is $2d\sin\theta$

To get a π phase shift bump must be $0.25(\lambda/\sin\theta) \approx 25\text{nm}$



Windows

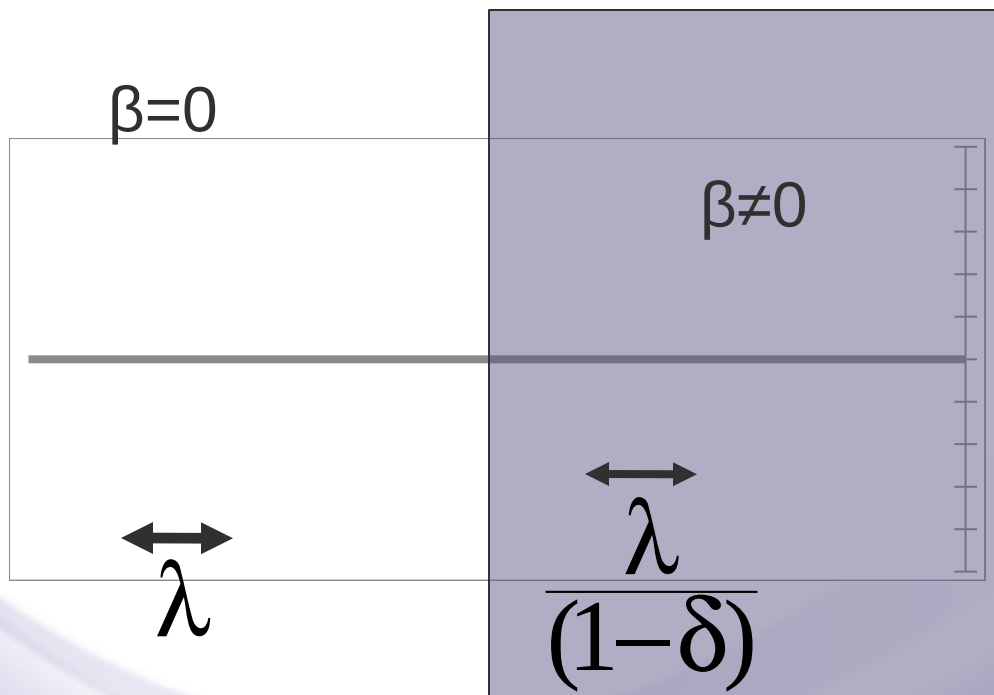
- Consider a Beryllium window
- To get a π phase shift bump must be $0.5(\lambda/\sin\theta) \approx 15\text{microns}$

A quick introduction to the kinoform

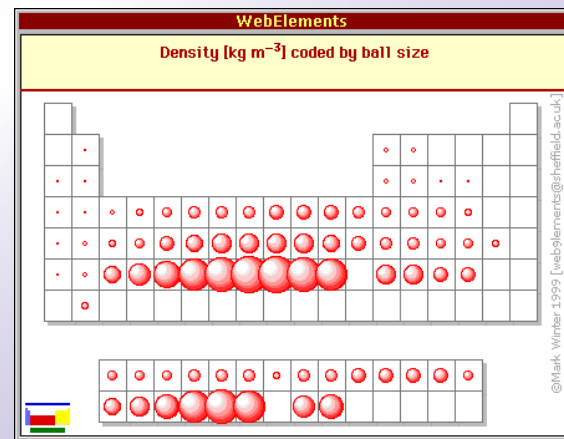
Optical Constants for Hard X-rays

Refractive index $n = 1 - \delta - i\beta$, where δ is $\sim 10^{-6}$

Phase velocity = c/n



Refractive index
set by Periodic
Table



$$\mathbf{E}(\mathbf{r}, t) = \underbrace{\mathbf{E}_0 e^{-i\omega(t-r/c)}}_{\text{vacuum propagation}} \underbrace{e^{-i(2\pi\delta/\lambda)r}}_{\phi\text{-shift}} \underbrace{e^{-(2\pi\beta/\lambda)r}}_{\text{decay}}$$

2π phase shift length

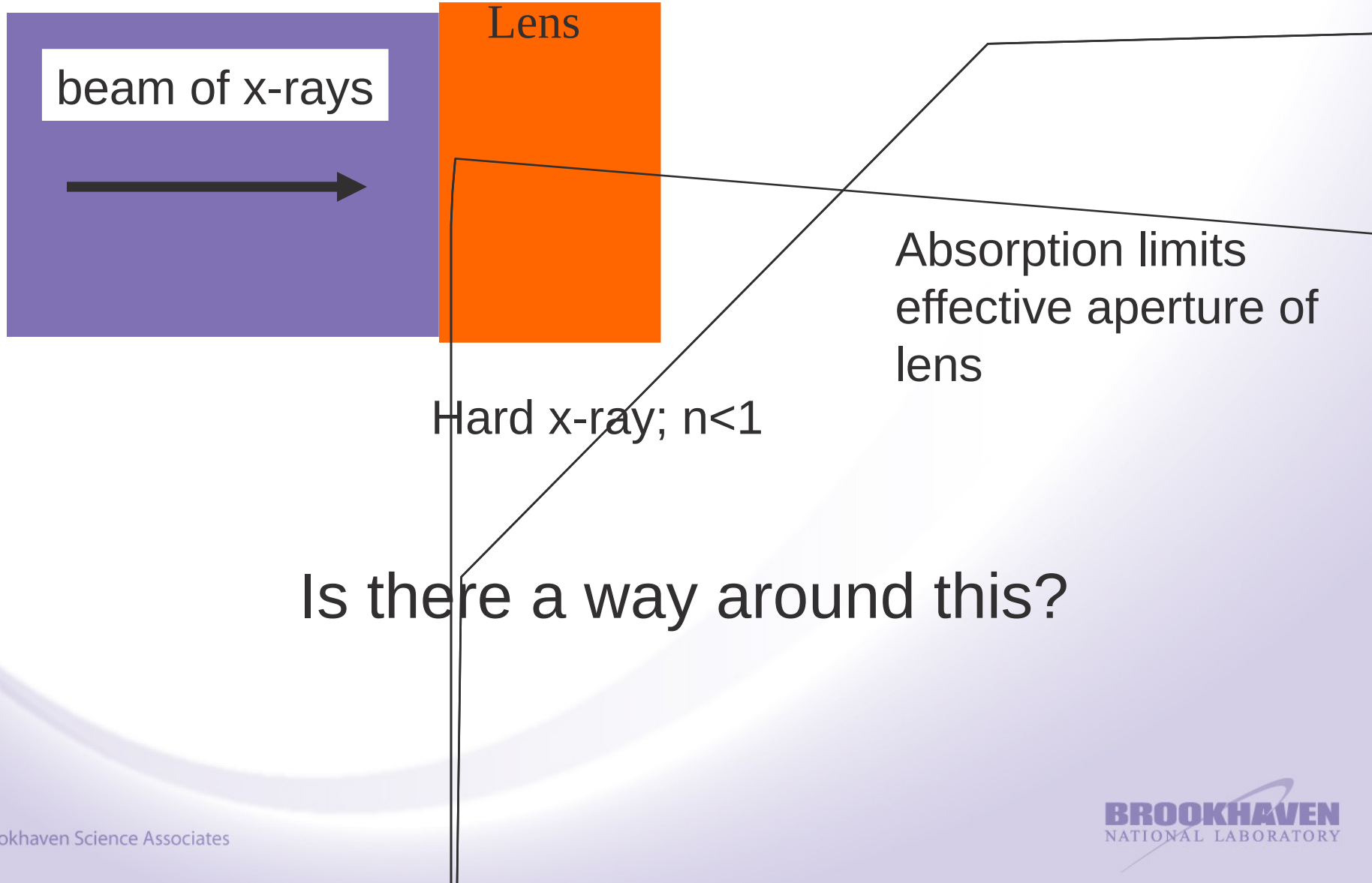
$$t_{2\pi} = \frac{\lambda}{\delta}$$

Exponential Decay length (Attenuation length) $l = \frac{\lambda}{4\pi\beta}$

Order of magnitude:

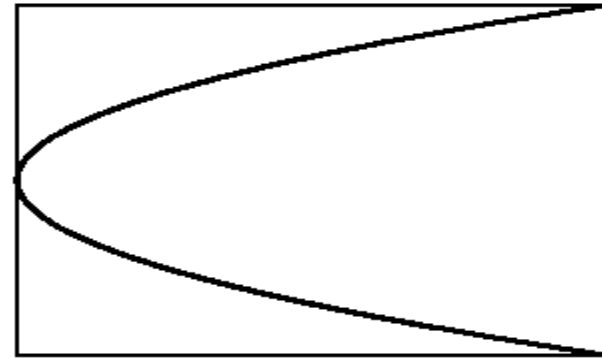
For Si, 12keV, $t_{2\pi} \approx (10^{-10} / 3 \times 10^{-6}) \approx 30$ microns

Absorption limits aperture and resolution

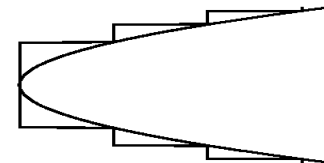


The way around the absorption limitation: Kinoform

Instead of solid refractive optic:



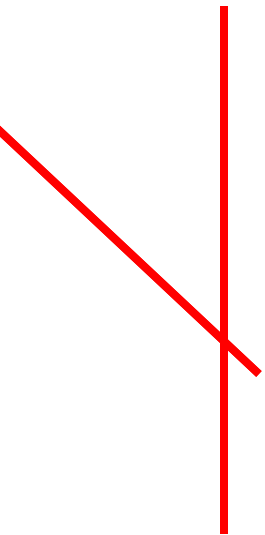
Use a kinoform (lighthouse solution):



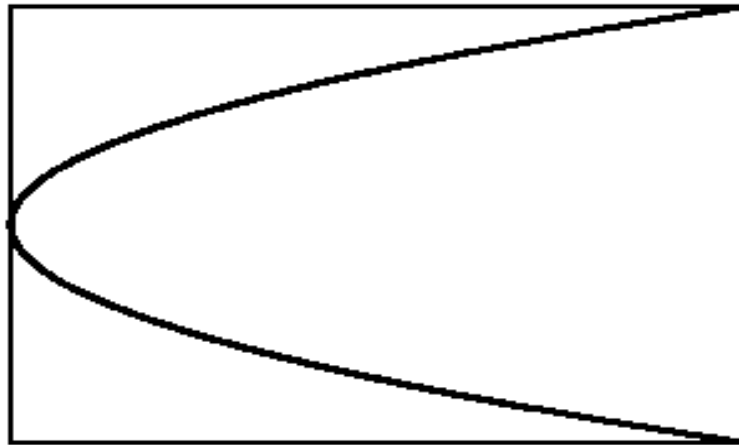
The effect of a refractive lens on single phase front

Using graphics instead of equations

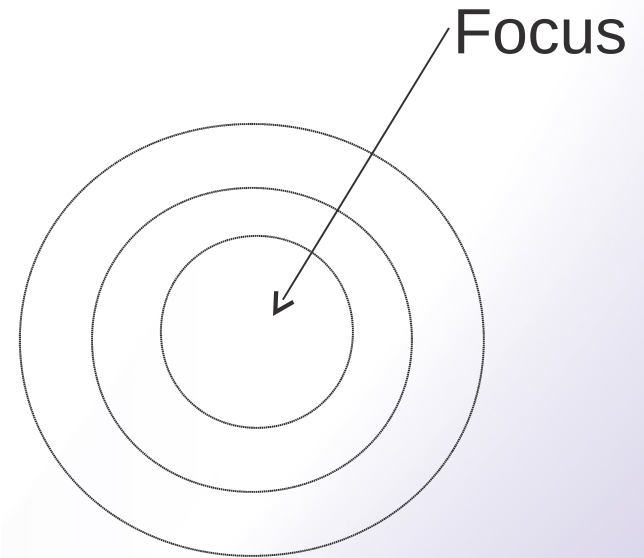
$$U(P_0) = \frac{1}{i\lambda} \iint_{(\xi, \eta)} U(P_1) \frac{\exp(ikr_{01})}{r_{01}} \cos \theta ds$$



Incoming
Phase front

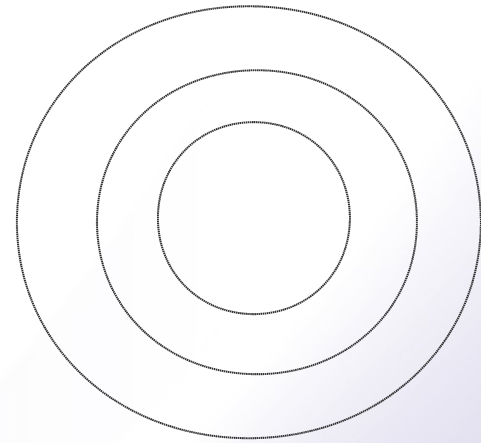
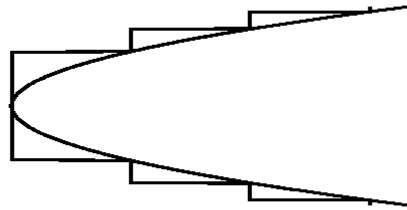


Lens



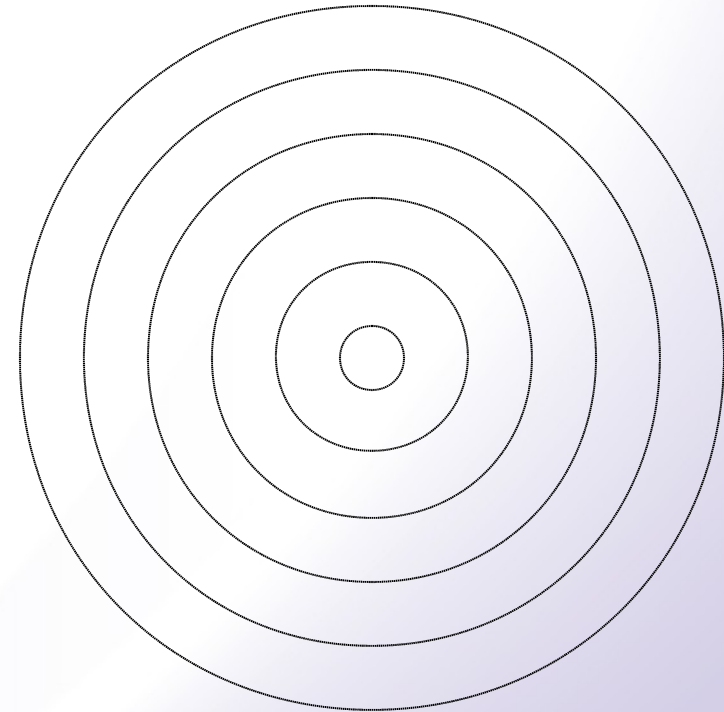
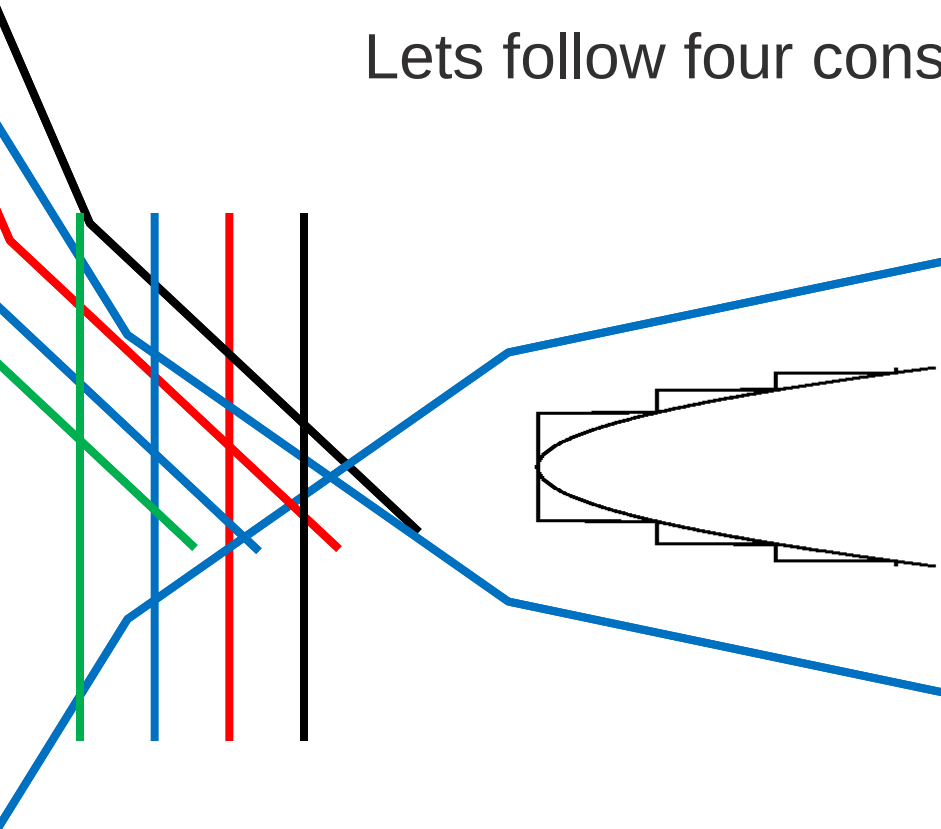
Focused
Phase front

The effect of a kinoform lens on single phase front



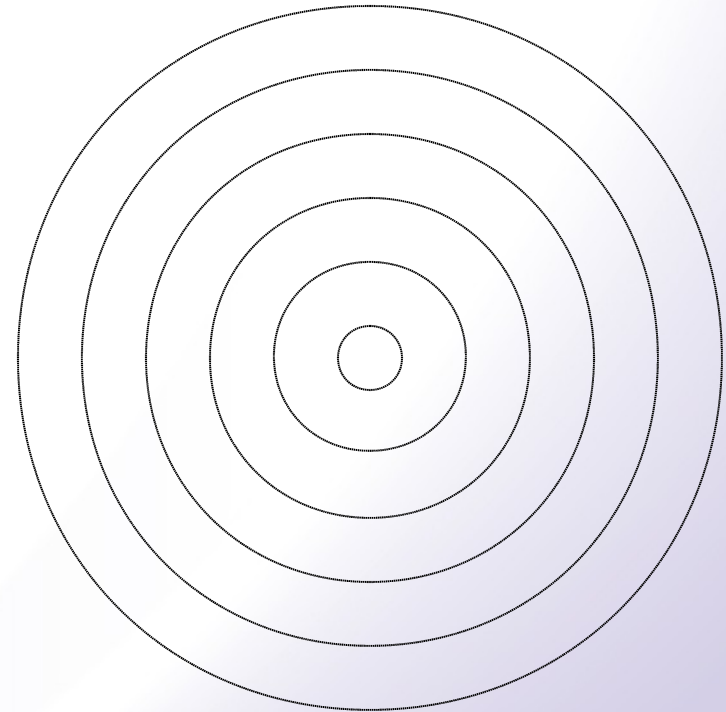
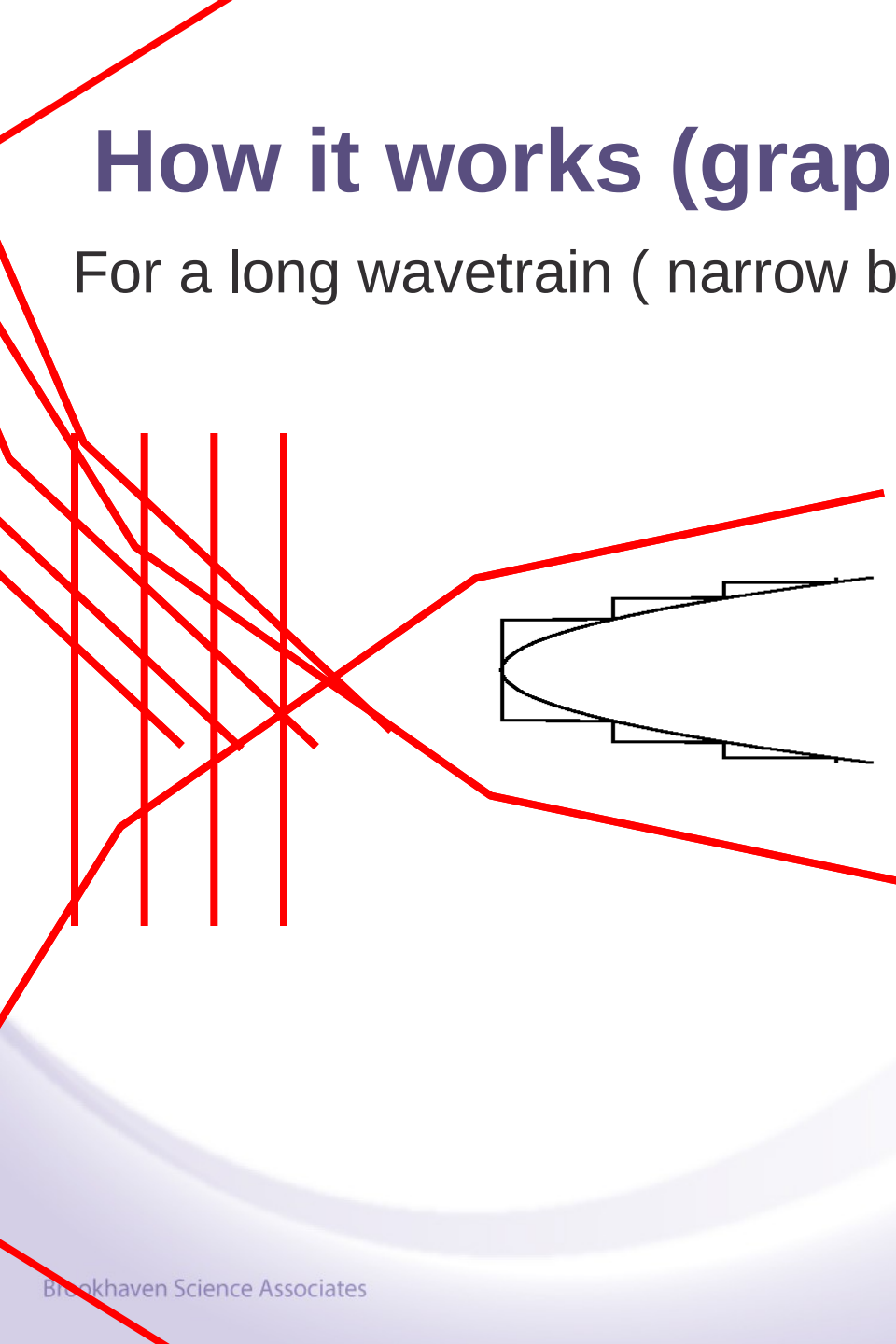
How it works (graphically)

Lets follow four consecutive phase fronts



How it works (graphically)

For a long wavetrain (narrow bandwidth) it is indistinguishable



Natural match to Micro-fabrication

The amount of material to give a 2π phase shift:

$$\frac{\lambda}{\delta} = \frac{0.1\text{nm}}{3 * 10^{-6}} = 30\mu\text{m}$$

Micro-electronics fabrication techniques will work!

In the old days: Lucent's Electron Beam writer JEOL 9300



Aaron Stein
CFN



Don Tennant

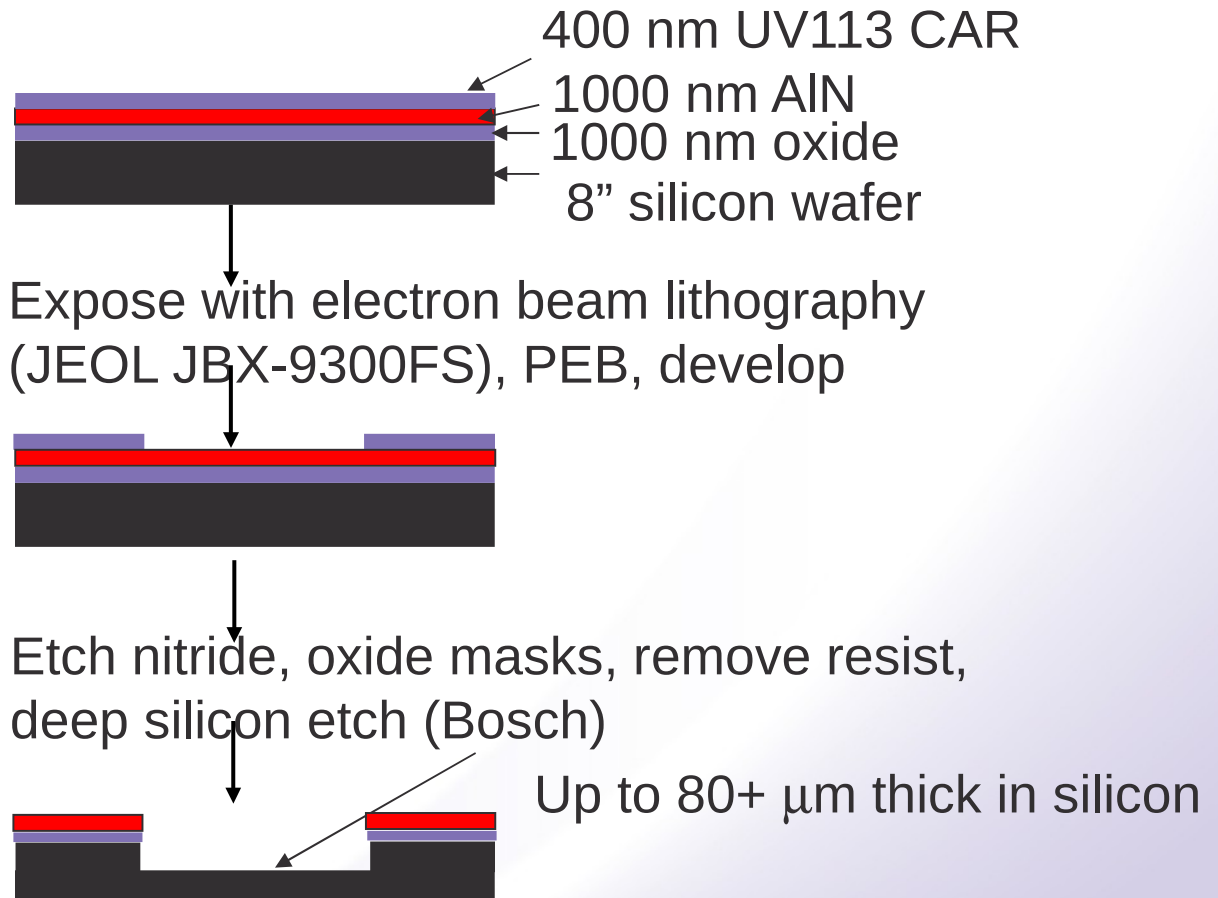
Important Characteristics:

Laser interferometer => Placement accuracy (4nm/500 μ m)

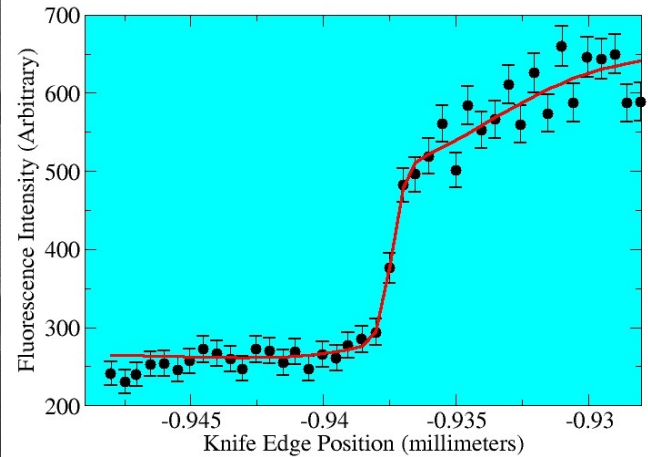
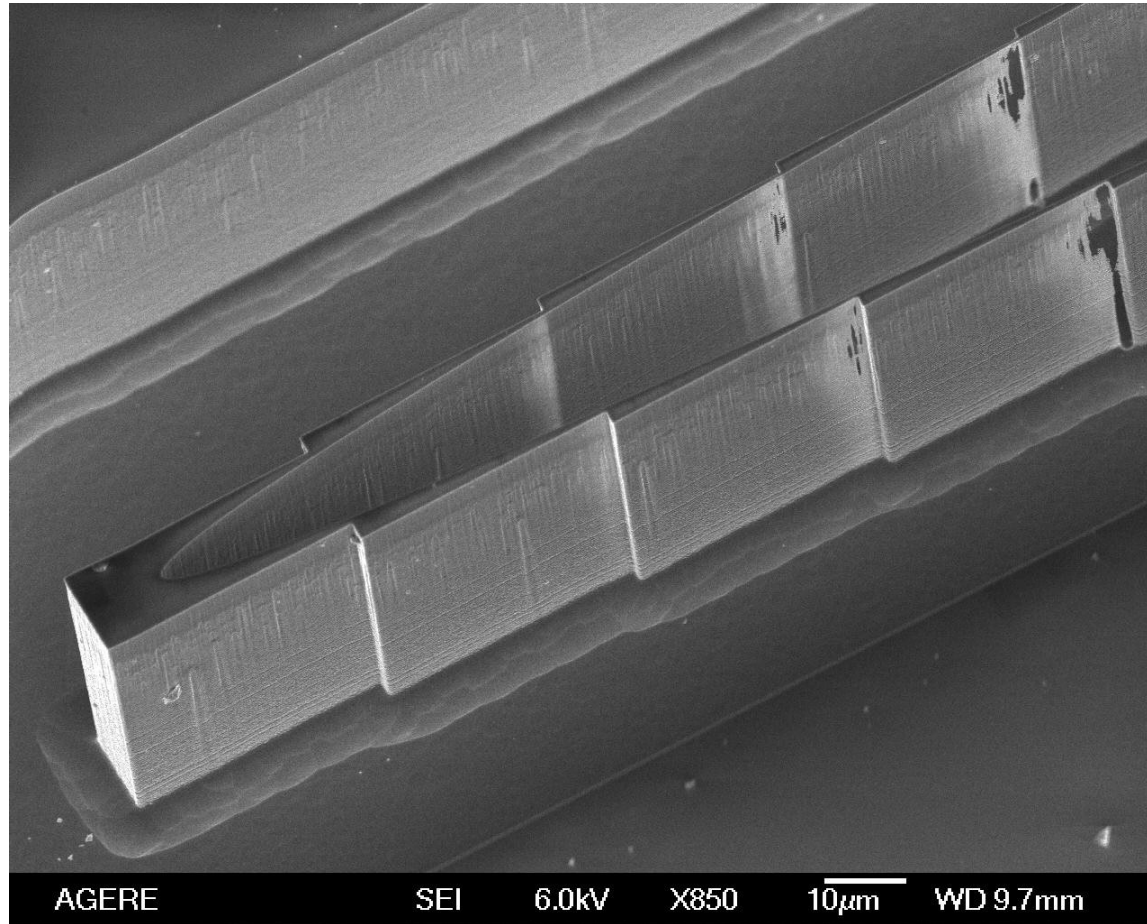
Flexible

Today: E-beam at CFN/BNL and etching at CNF/Cornell

Fabrication Process Flow



Sub-micron spots with >100 micron aperture

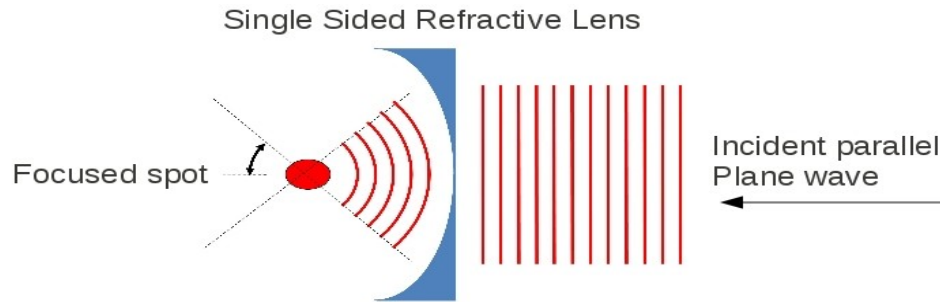


James Ablett

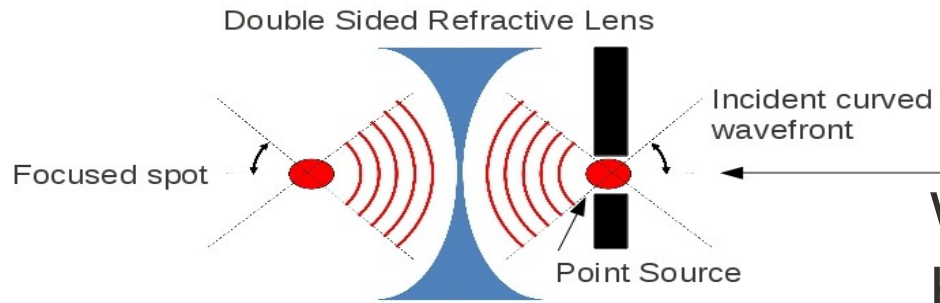
- Figure on right shows a knife edge scan
- Efficiency is greater than 60%

And now back to X6A

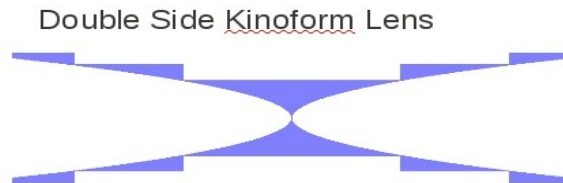
One more wrinkle for us, the source is not at infinity



This is our conventional case
the source is at infinity

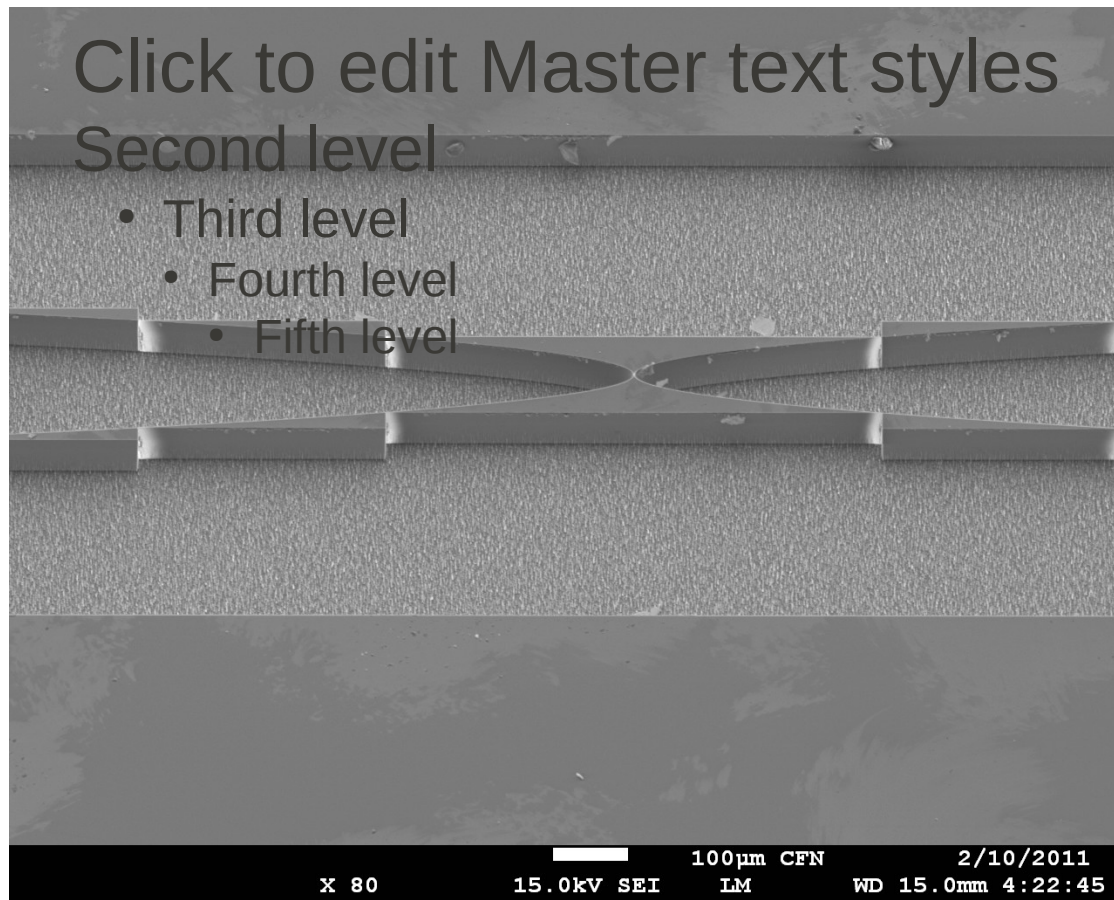


We need to re-design the lens
because the source is closer

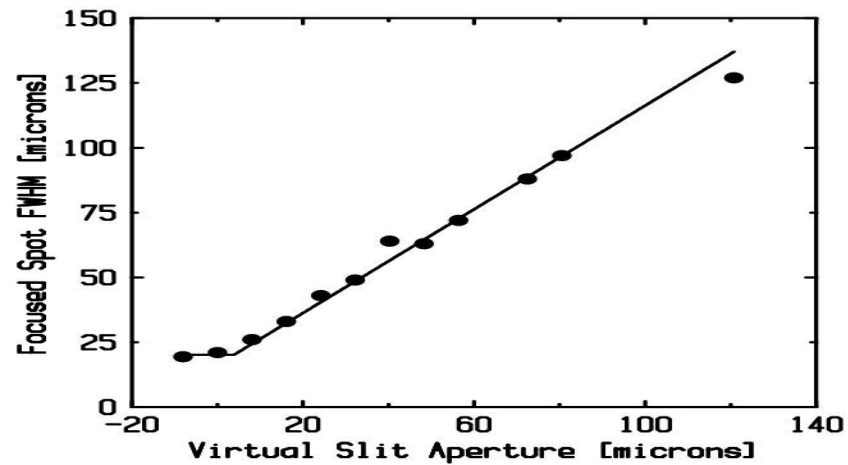


← We need to do this

Close up view (SEM) of actual back to back kinoform lens

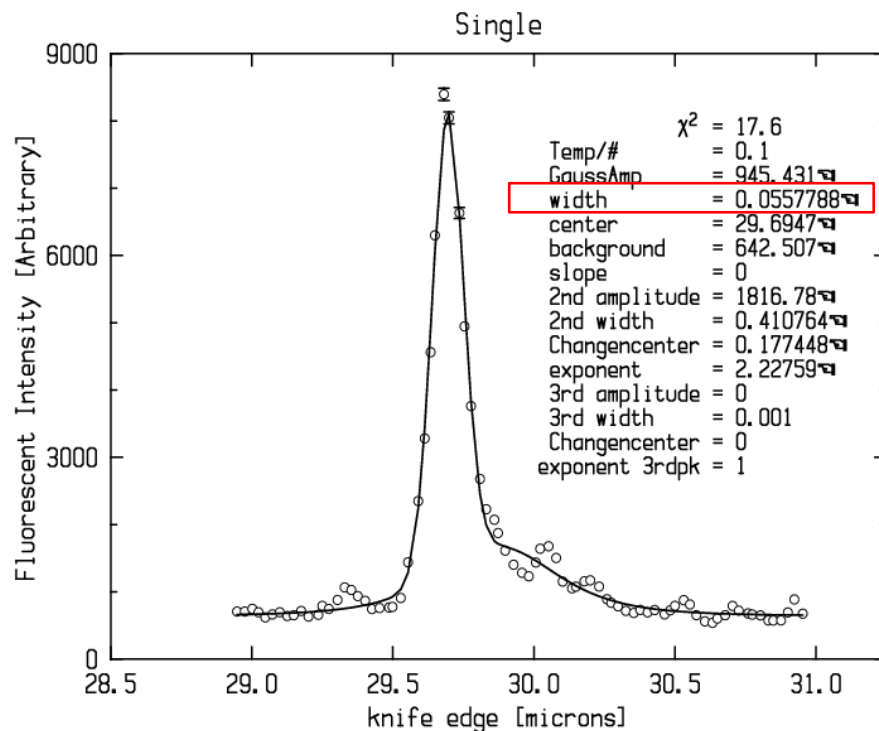


Result;
Measured spot at sample depends on to virtual slit size



Some other applications we have had for kinoforms

Diffraction limited performance from a Single Lens



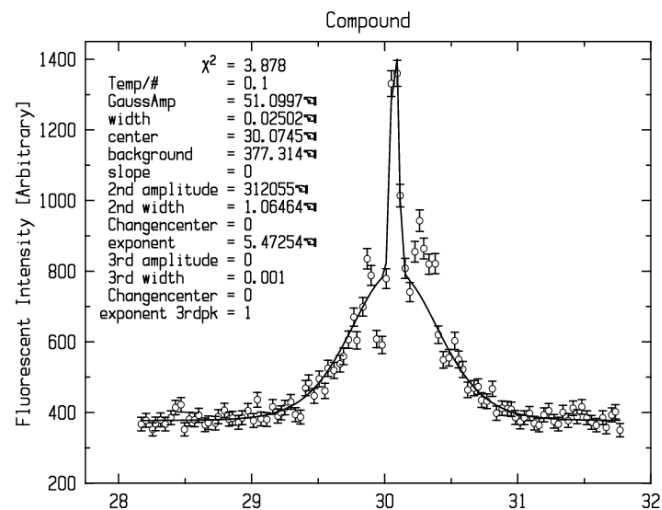
Close to Diffraction limited performance

200micron aperture

Sigma = 56nm

=> FWHM=2.35 σ =131nm

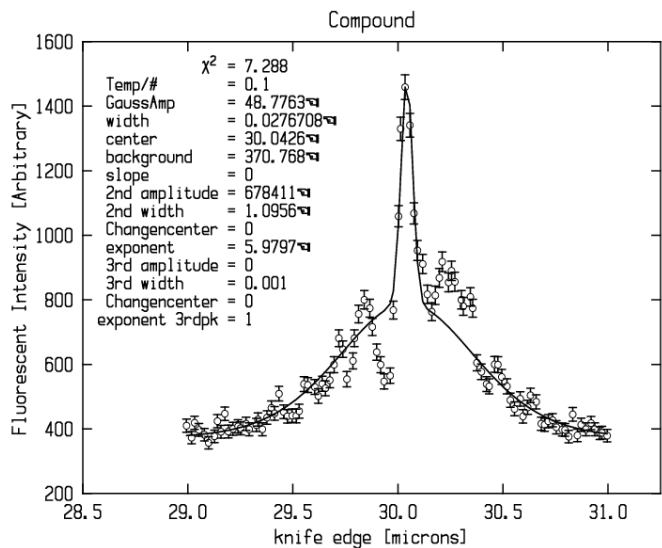
Compound Lens



- 8 lens array

- Measurement ran out of time, not yet at best focus

- Sigma = 25nm (FWHM= 59nm)

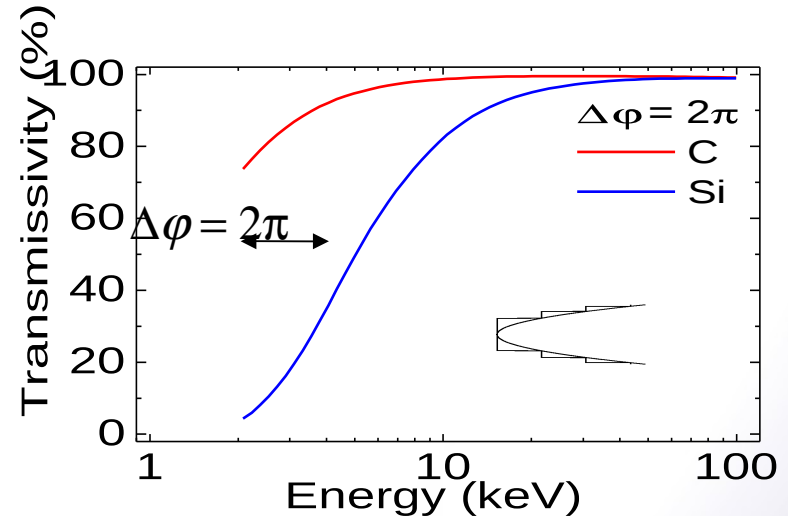


- Knife edge is 30nm of Cr deposited on Si

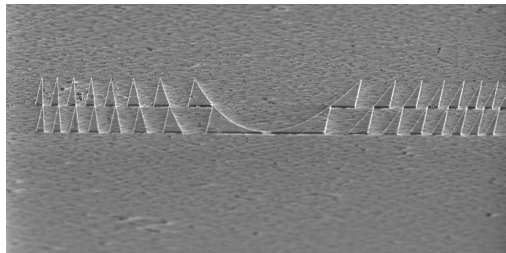
- So actually the real, de-convolved performance is better !

Diamond Kinoform: fabrication and testing*

Why: Diamond has better transmission than silicon at lower energies



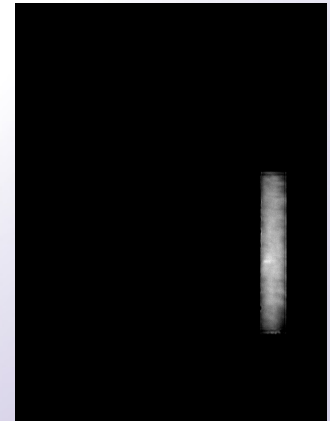
A real diamond lens:



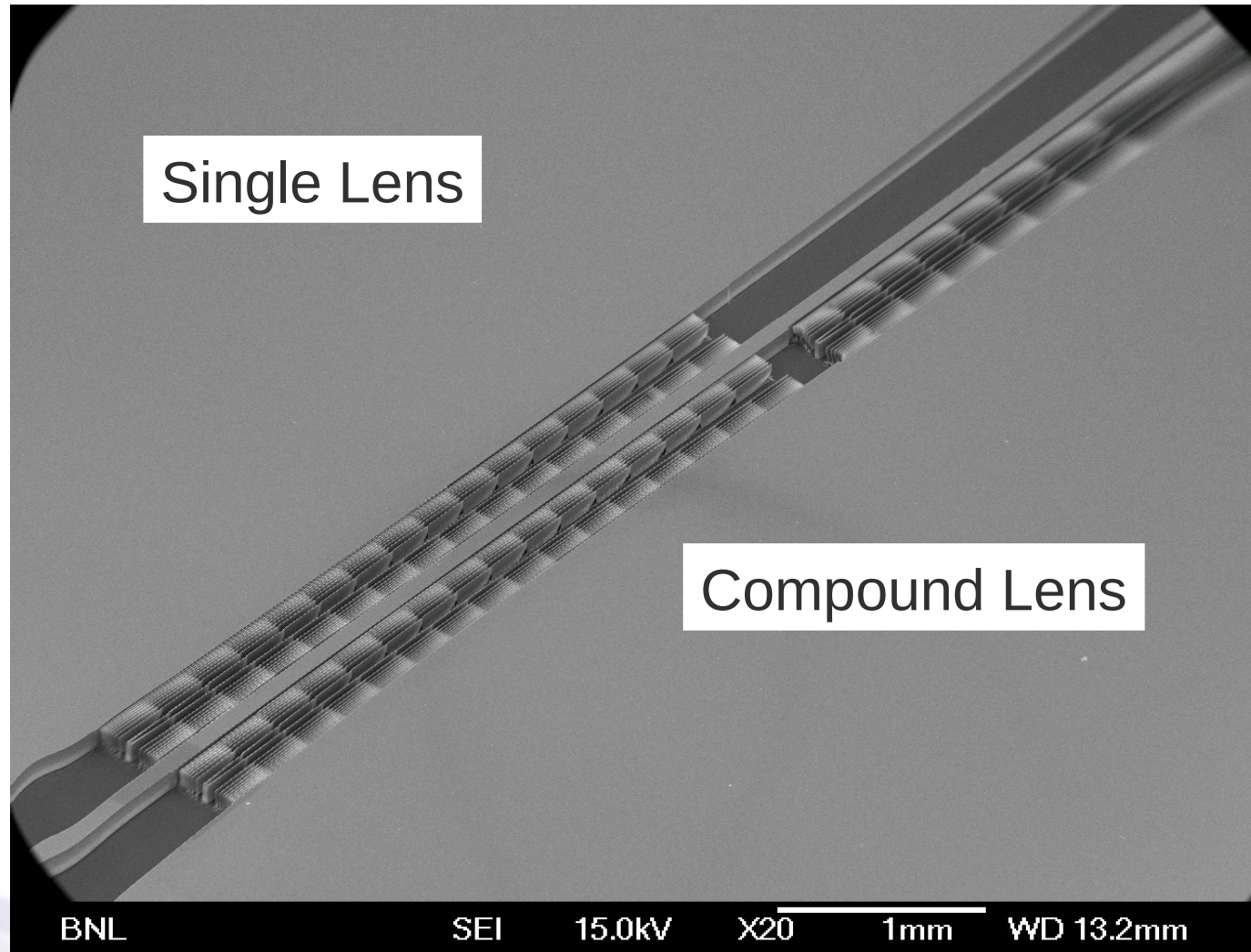
and it works! →

(not very well but we know what to do next)

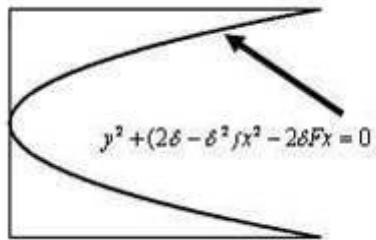
Line focus



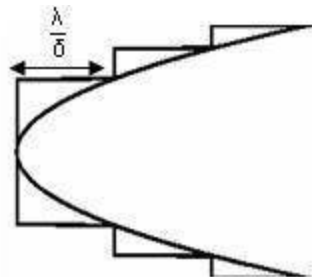
First compound lens to exceed critical angle



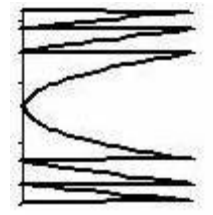
•“Using Compound Kinoform Hard-X-Ray Lenses to Exceed the Critical Angle Limit”, K. Evans-Lutterodt, A. Stein, J. M. Ablett, N. Bozovic, A. Taylor and D.M. Tennant, Phys. Rev. Lett. 99, 134801 (2007)



Solid Refractive



Long Kinoform



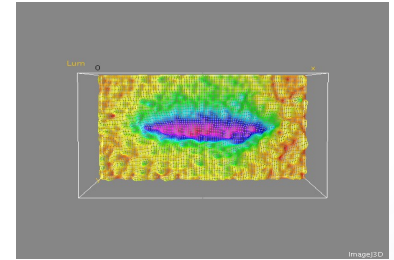
Short Kinoform

Focusing at high energies (30 keV)

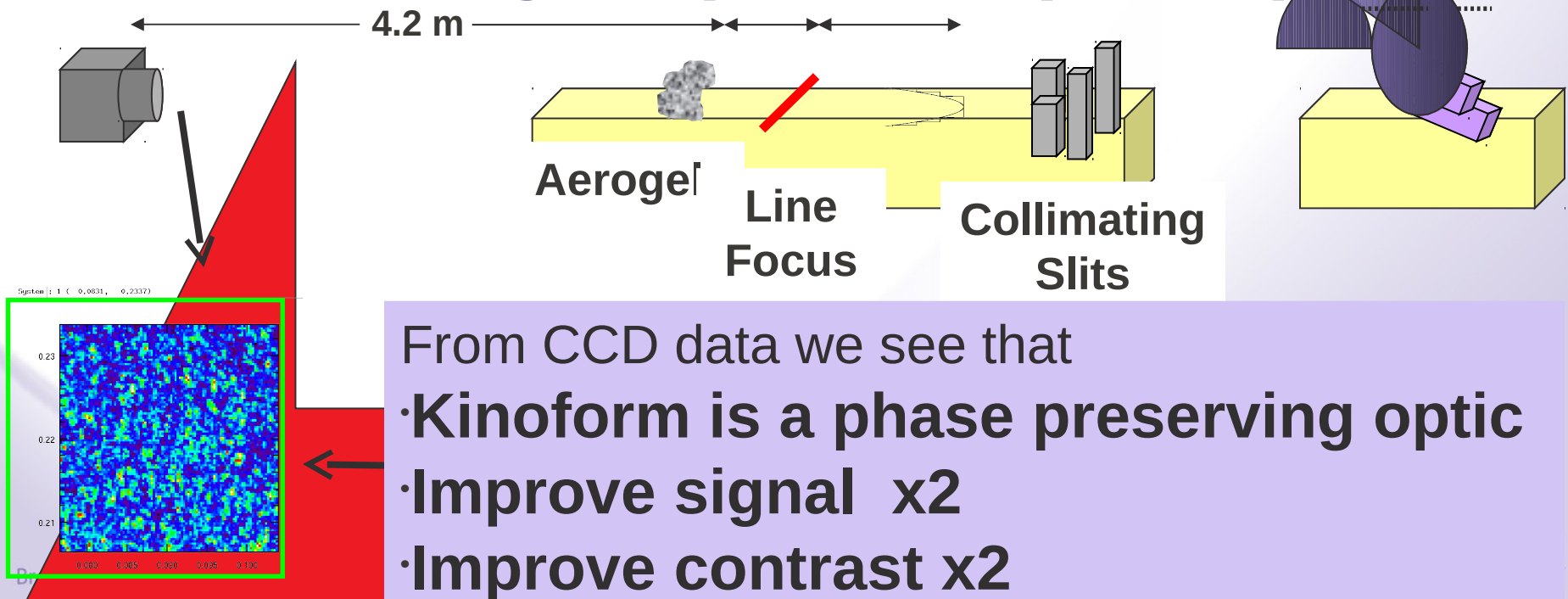
Image of focused line at 30 keV (Dr Guo)

Spot size at x17 is approximately 8 microns

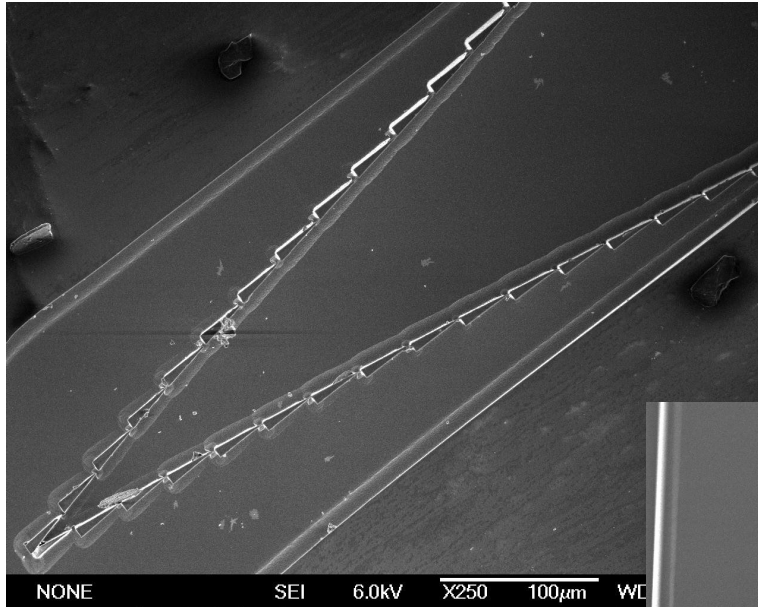
Applications: High Pressure, Temperature study of materials



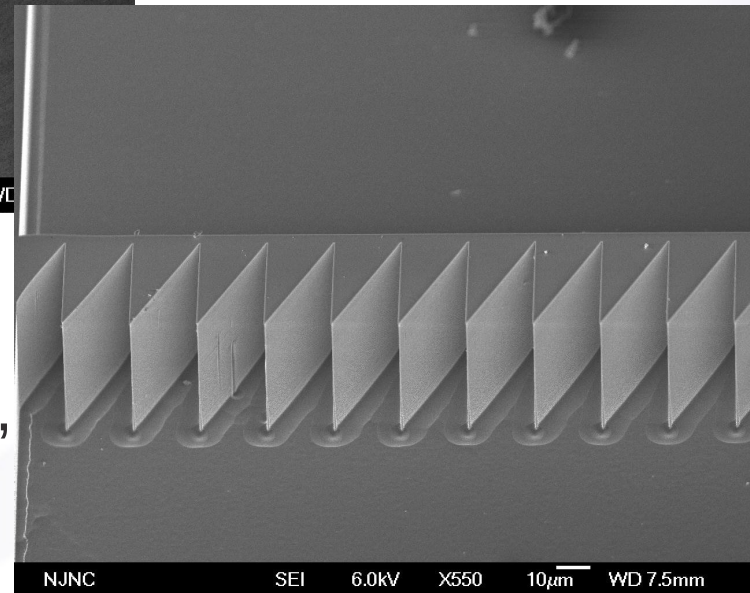
And low energies (7.35 keV) for speckle



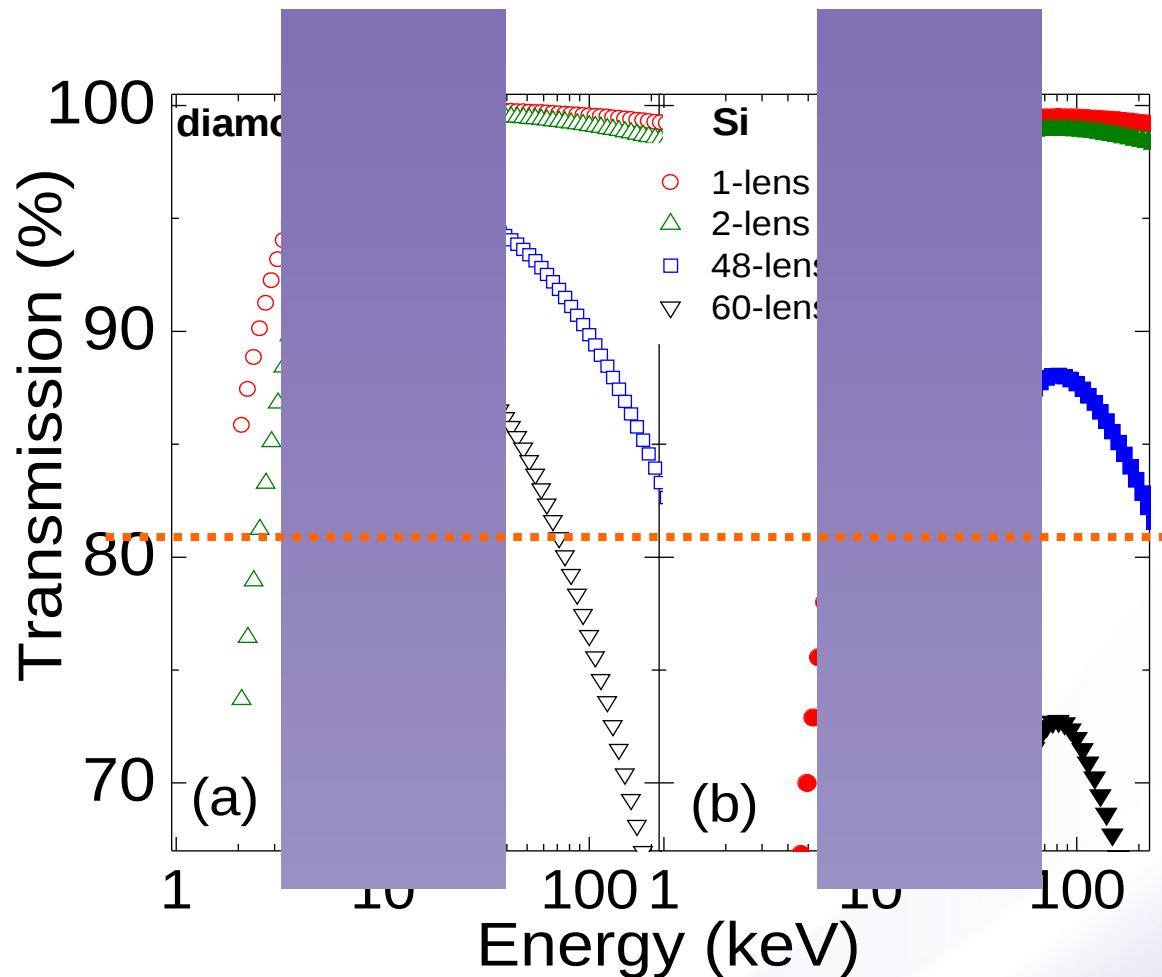
We can make prisms too



Now we have lenses and prisms,
Will allow “optical workbench”



Advantages of diamond for the same lens configuration. I

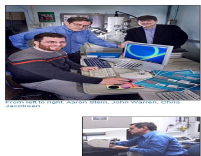


Source: NIST Tables and cross checked with CXRO <30keV
Compton + Photo-electric

A Diamond X-ray Lens!



Abdel Isakovic



John Warren

